

- 1 **Supplementary information**
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- 3 **Bioinspired, electroactive colorable and additive manufactured photonic artificial**
- 4 **muscle**
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- 13 **Movie 1. Coloration behavior of Anna's hummingbird's crown and gorget feathers**
- 14 **(Courtesy of Mick Thompson for authorization).**
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- 16 **displacement sensor and the line laser displacement sensor.**
- 17 **Movie 3. Color change response of FlexAM under applied voltages.**
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- 19 **Movie 5. Patterns of the photonic display.**
- 20

## 21 Additive Manufacture of FlexAM

22 The detailed preparation process of photonic layer is shown in Fig. S1a. A silicon wafer,  
23 with hexagonal pillar array in nanoscale (period 600 nm, diameter 300 nm, depth 500 nm, and  
24 area  $20 \times 20 \text{ mm}^2$ ) on the surface, was used as the template to demold the flexible photonic  
25 layer. After 5 minutes of complete mixing with a stirrer and sufficient vacuum degassing, the  
26 liquid Polydimethylsiloxane (Sylgard 184) was poured on the silicon wafer template. A film  
27 applicator with a preset height is used to cast the liquid Sylgard 184 to ensure its thickness  
28 agrees the preset value. After degassing again, the film was cured at  $70 \text{ }^\circ\text{C}$  for 3 hours in the  
29 oven. Finally, the cured silicone rubber film was carefully peel off from the template to obtain  
30 photonic layer.

31 The multilayer structure of FlexAM includes protective layers, DE layers and compliant  
32 electrodes. The protective layer, which plays the role of encapsulating the compliant electrode,  
33 was made of a platinum-catalyzed silicone rubber (Ecoflex-0020). The DE layer was prepared  
34 of Polydimethylsiloxane (Sylgard 186). A tape casting machine (PF400-H, Lebo, China) was  
35 used to fabricate FlexAM, specific preparation parameters include:  $100 \sim 400 \text{ }\mu\text{m}$  for the preset  
36 height of the applicator,  $5 \text{ mm} \cdot \text{s}^{-1}$  for the casting speed, 2 mm for the width of the applicator's  
37 blade. The casting liquid oligomer is heated at  $70 \text{ }^\circ\text{C}$  for two hours to finally obtain a solid  
38 film whose thickness is empirically half of the preset thickness. The specific preparation  
39 process is shown in Fig. S1b, to help understand, the thickness of DEA is appropriately  
40 exaggerated during the process of tape casting multi-layers, (i) Casting the oligomer (Ecoflex-  
41 0020) as a protective layer on the substrate by the applicator. (ii) Curing the liquid layer at  $70$   
42  $^\circ\text{C}$  for two hours. (iii) The laser-cut PET mask was covered on the dry layer. (iv) Evenly spray  
43 the graphite powder on the exposed area of the silicone layer as compliant electrodes by a  
44 spray gun. (v) Gently remove the mask. (vi) Casting PDMS oligomer (Sylgard 186, Dow  
45 Corning, USA) as the DE film. Repeat step (ii) to (vi) for several times until the number of  
46 layers reaches our design. (vii) Casting the final protective layer to encapsulate the electrode.  
47 Multilayer structures are obtained by laser-cutting for step (viii). (ix) Attaching the photonic  
48 layer on the surface of the DEA. Finally, FlexAM samples were obtained. Because FlexAM  
49 and photonic layer are the same material system and have a small amount of viscosity on the

50 surface, they are self-bonded at the surface with a reliable mechanical connection between the  
51 two.

## 52 Deformation of FlexAM by voltage actuation

53 Since the nanoscale structure on the surface of the photonic layer will not affect the  
 54 voltage-induced deformation of the FlexAM, the photonic layer is modelled as a passive layer  
 55 serving as a mechanical constraint. We give the following assumptions: (i) all deformation is  
 56 in static equilibrium, (ii) the FlexAM is regarded as an Euler-Bernoulli beam, (iii) the bending  
 57 deformation of FlexAM along the width direction is negligible, (iv) no slip on the bonding  
 58 surfaces of the layers, (iv) the thickness of the electrodes is ignored, (v) all silicone layers are  
 59 considered linear elastic under small deformations. The geometry of FlexAM subjected to an  
 60 electric field is sketched in Fig. S5 which illustrates the section along the length of a n-layer  
 61 FlexAM. For any i-th layer, it has a specific Young's modulus  $Y_i$ , relative permittivity  $\epsilon_{ri}$   
 62 and Poisson's ratio  $\nu_i$ . The fixed support point of the bottom surface is defined as the origin  
 63 of coordinates, the X axis is along the length of the FlexAM and the Z axis is in the thickness  
 64 direction. The Z-axis coordinates of the upper and lower surfaces of the i-th layer are  $Z_{i+1}$  and  
 65  $Z_i$ , respectively. The radius of curvature of any cross section is  $\rho$ . The strain of i-th layer  
 66 along the X axis can be expressed as:

$$67 \quad \epsilon_i = \epsilon_{iElastic} + \epsilon_{iMaxwell} \quad (1)$$

68 where the  $\epsilon_{iElastic}$  is the elastic strain by elastic stretch or compress,  $\epsilon_{iMaxwell}$  is the strain due  
 69 to the Poisson effect caused by the Maxwell stress generated by the electric field  $E$  in the  
 70 thickness direction:

$$71 \quad \epsilon_{iMaxwell} = \nu_i \frac{\epsilon_0 \epsilon_{ri}}{Y_i} E^2 = \nu_i \frac{\epsilon_0 \epsilon_{ri} U^2}{Y_i (Z_{i+1} - Z_i)^2} \quad (2)$$

72 Here the  $\epsilon_0$  is the permittivity constant in vacuum ( $8.852 \times 10^{-12} F \cdot m^{-1}$ ),  $U$  is the applied voltage.  
 73 The elastic strain in Equation 1 can be rewritten as:  $\epsilon_{iElastic} = \sigma_i / Y_i$ . Assuming the Z-axis  
 74 coordinate of neutral layer is  $Z_{na}$ , for any point on the beam with the coordinate is  $Z$ , the  
 75 axial strain can be written as:

$$\varepsilon_i = \frac{Z_{na} - Z}{\rho} \quad (3)$$

76

77 Combining the above equations, the axial stress of any position can be expressed as:

$$\sigma_i = Y_i \left( \frac{Z_{na} - Z}{\rho} - \frac{v_i \varepsilon_0 \varepsilon_{ri}}{Y_i (Z_{i+1} - Z_i)^2} U^2 \right) \quad (4)$$

78

79 For the protective layer and photonic layer which no electric field is applied, the relative  
80 permittivity is set to zero. For any section perpendicular to the axial direction, the force  
81 balance and moment balance can be obtained as:

$$\begin{aligned} \sum F &= \sum_{i=1}^n b \int_{z_i}^{z_{i+1}} \sigma_i dz = \sum_{i=1}^n b \int_{z_i}^{z_{i+1}} Y_i \left( \frac{Z_{na} - Z}{\rho} - \frac{v_i \varepsilon_0 \varepsilon_{ri}}{Y_i (Z_{i+1} - Z_i)^2} U^2 \right) dz = 0 \\ \sum M &= \sum_{i=1}^n b \int_{z_i}^{z_{i+1}} \sigma_i z dz = \sum_{i=1}^n b \int_{z_i}^{z_{i+1}} Y_i \left( \frac{Z_{na} - Z}{\rho} - \frac{v_i \varepsilon_0 \varepsilon_{ri}}{Y_i (Z_{i+1} - Z_i)^2} U^2 \right) z dz = 0 \end{aligned} \quad (5)$$

82

83 After the derivation, we can obtain the radius of curvature of any point on the neutral layer:

$$\rho = \frac{\frac{1}{4} \left[ \sum_{i=1}^n Y_i (Z_{i+1}^2 - Z_i^2) \right]^2 - \frac{1}{3} \sum_{i=1}^n Y_i (Z_{i+1} - Z_i) \sum_{i=1}^n Y_i (Z_{i+1}^3 - Z_i^3)}{\frac{U^2}{2} \cdot \sum_{i=1}^n Y_i (Z_{i+1} - Z_i) \sum_{i=1}^n \left( v_i \varepsilon_0 \varepsilon_{ri} \frac{Z_{i+1} + Z_i}{Z_{i+1} - Z_i} \right) - \frac{U^2}{2} \sum_{i=1}^n \frac{v_i \varepsilon_0 \varepsilon_{ri}}{Z_{i+1} - Z_i} \sum_{i=1}^n Y_i (Z_{i+1}^2 - Z_i^2)} \quad (6)$$

84

85 In this formula, we find that the radius of curvature is a constant, and it is only related to the  
86 material, structural parameters and applied voltage of the FlexAM. Therefore, the deformation  
87 of FlexAM is actually a pure bending, and the shape of FlexAM after voltage is a circular arc.  
88 The radius of the arc is the radius of curvature obtained in Equation 6. Since the elongation of  
89 the FlexAM is sufficiently small that can be ignored with the voltage on, the length of the arc  
90 is equal to the length  $L$  of the FlexAM before the deformation. We can obtain the deflection

91 angle of the actuator's tip,  $\theta_L = L/\rho$ . The deflection and the deflection angle are both zero at  
92 the fixed end, so the coordinate position of any point on FlexAM neutral layer can be derived  
93 as:

$$\begin{cases} x = \rho \sin \theta \\ y = \rho - \rho \cos \theta \end{cases} \quad \theta \in [0, \theta_L] \quad (7)$$

94

95 It should be noted that since the bending deformation of FlexAM is considered as  
96 plane strain, the Poisson's ratio and Young's modulus in the above derivation formula need

97 to be corrected as follows:

$$V_{i\ plane\_strain} = \frac{V_i}{1 - V_i} \quad Y_{i\ plane\_strain} = \frac{Y_i}{1 - V_i^2} \quad (8)$$

### 99 Color change of FlexAM under applied voltage

100 Based on the fact that we have verified that the angle dependence of photonic layer can  
 101 be explained by the grating diffraction equation, in this section, we combine the  
 102 electromechanical response formula derived above and the grating diffraction equation to  
 103 obtain the coupling between the structural color's wavelength and applied voltage on the  
 104 FlexAM. As shown in Fig. S6, in the initial coordinate system  $X1-Y1$ , the parallel light is  
 105 irradiated on the undeformed FlexAM at the incident angle of  $\theta_i$ , the observer and the light  
 106 source are on the same side of the normal, and the observation angle is  $\theta_n$ . Considering the  
 107 far distance between the light source and the observer from the FlexAM, the error of the  
 108 incident angle and the observation angle due to the length of the FlexAM is ignored. After  
 109 the voltage is applied, the point initially at the position  $l_0$  moves to  $(x_0, y_0)$ , the deflection  
 110 angle is:

$$\theta_\alpha = \theta_L \cdot \frac{l_0}{L} \quad (9)$$

112 The coordinate can be obtained as:

$$\begin{cases} x_0 = \rho \sin \theta_\alpha \\ y_0 = \rho - \rho \cos \theta_\alpha \end{cases} \quad \theta_\alpha \in [0, \theta_L] \quad (10)$$

114 And the incident angle and observation angle of this point change into  $\theta_i - \theta_\alpha$  and  $\theta_n - \theta_\alpha$ ,  
 115 respectively. According to the grating diffraction equation, the central bandwidth of the  
 116 structural color that can be observed at this point is:

$$\lambda_i = d [\sin(\theta_i - \theta_\alpha) + \sin(\theta_n - \theta_\alpha)] \quad (11)$$

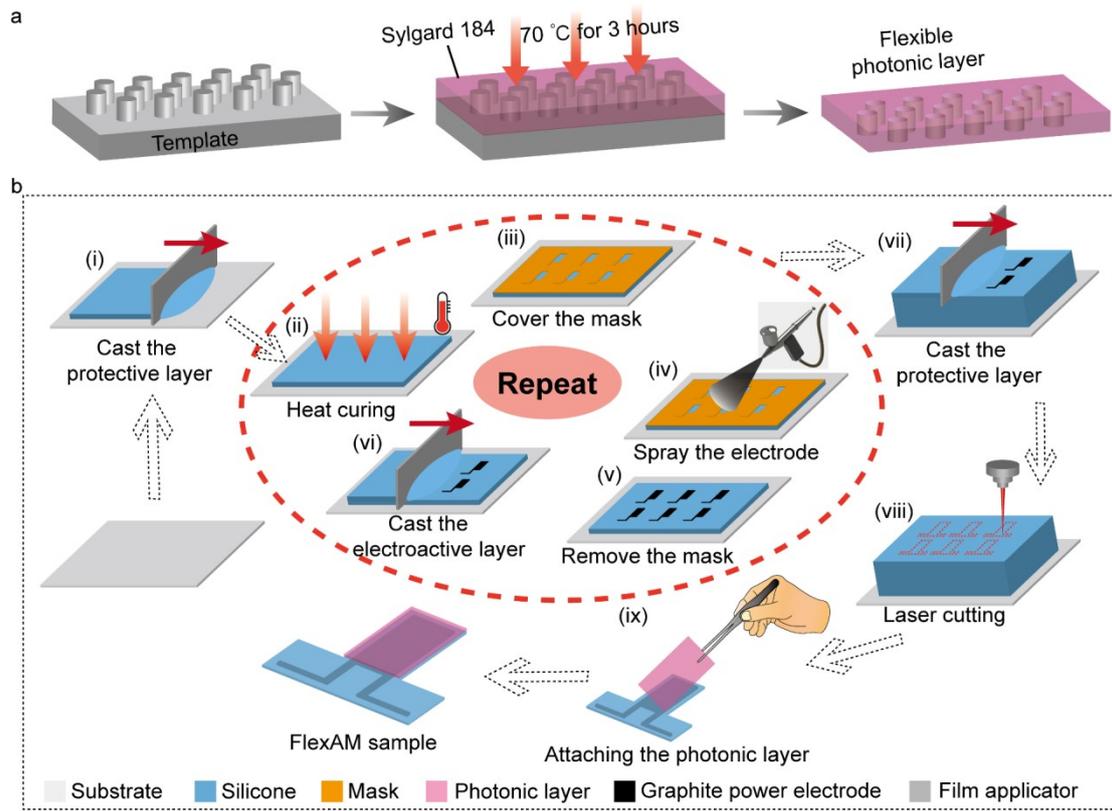
118 In order to intuitively obtain the rainbow-like structural color band on FlexAM seen by  
 119 the observer, the deformed FlexAM is directly projected on a plane perpendicular to the  
 120 initial observation angle  $\theta_n$ , which can be expressed as:

121 
$$x_i = x_0 \cos \theta_n + y_0 \sin \theta_n \quad (12)$$

122 **Structural parameters optimization of FlexAM**

123 Based on the results of FlexAM samples with different aspect ratios being used to  
124 verify the accuracy of the above theoretical model, we compared the influence of various  
125 structural parameters on the electromechanical response in this section. Five main  
126 parameters were selected to design the orthogonal experimental calculation and the specific  
127 values are shown in Table S1 (The length of the actuator was selected as 15 mm). The  
128 calculation results show that the smaller values of the five parameters yield a more  
129 significant the bending deformation of FlexAM. However, considering the precision  
130 limitations of the fabrication technique and the requirement for FlexAM to have moderate  
131 operation output, we have to appropriately compromise on the selection of some of the  
132 parameters. By comparing the extreme difference of each parameter (Fig. S7a), we  
133 concluded that the thickness of the DE layer and the number of DE layers have the most  
134 significant influence on the actuation, and it can be negligible for the rest three parameters.  
135 Fig. S7b to S7f indicate the influence of multiple single parameters on the actuation effect  
136 on the basis of the optimal parameters obtained by the orthogonal experiment. Finally, we  
137 chosen the five parameters P1~P5 as 200  $\mu\text{m}$ , 50  $\mu\text{m}$ , 150  $\mu\text{m}$ , 3  $\mu\text{m}$  and 50  $\mu\text{m}$ .  
138 Corresponding tip angle deformation is 29.48° which covers the design goal of 15°  
139 proposed in the section of angle dependent characterization of photonic layer.

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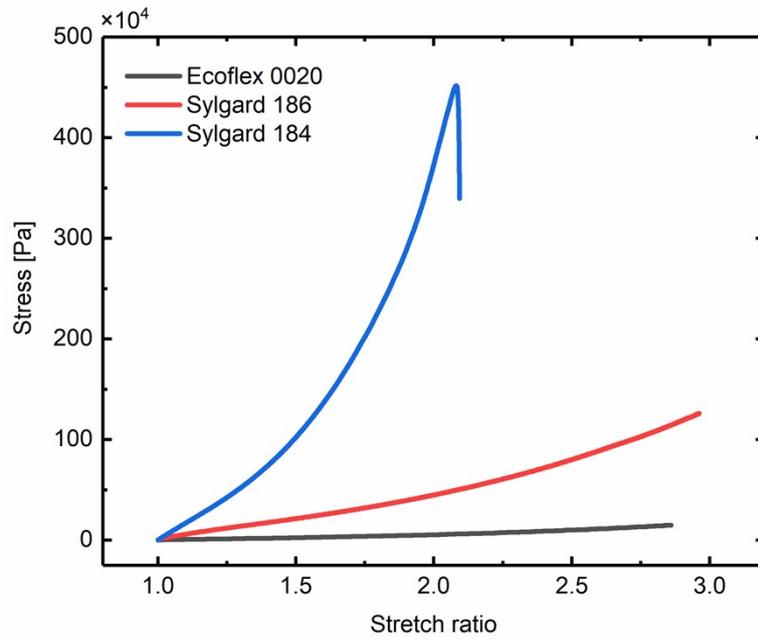


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142 **Fig. S1.** Fabrication process FlexAM. (a) Fabrication process of photonic layer. (b) Laminated

143 object manufacture (LOM) process of FlexAM.

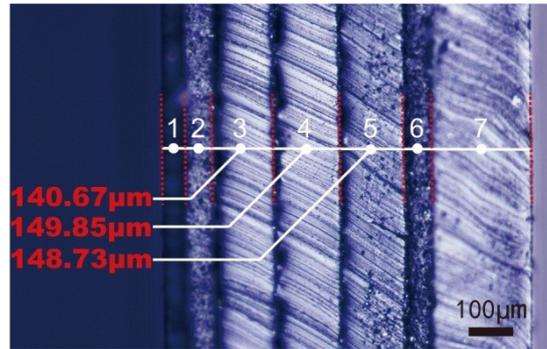
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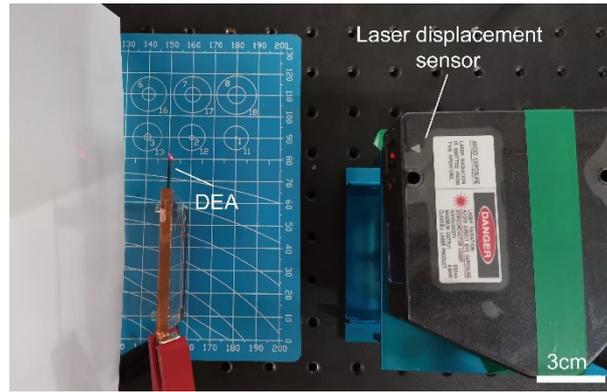
146 **Fig. S2.** The relationship between tensile stress and stretch amount of three silicone rubber  
147 materials.

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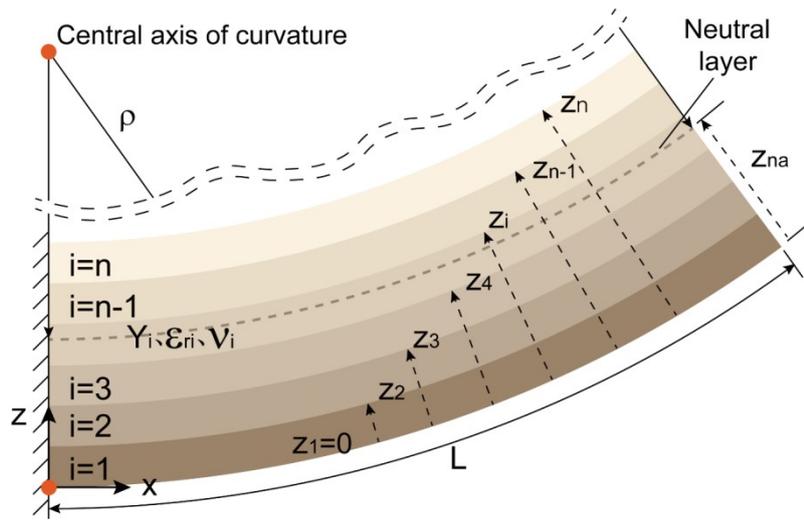
150 **Fig. S3.** Cross section of FlexAM under optical microscope, layer 1 is the PET substrate,  
151 layer 2 and 6 are the protective layers, layer 3~5 are the DE actuation layers and layer 7 is  
152 the photonic layer.



154

155 **Fig. S4.** Experimental setup for measuring FlexAM's tip deflection under cyclic voltage  
156 load.

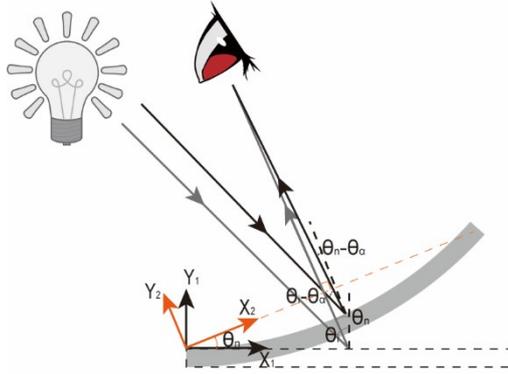
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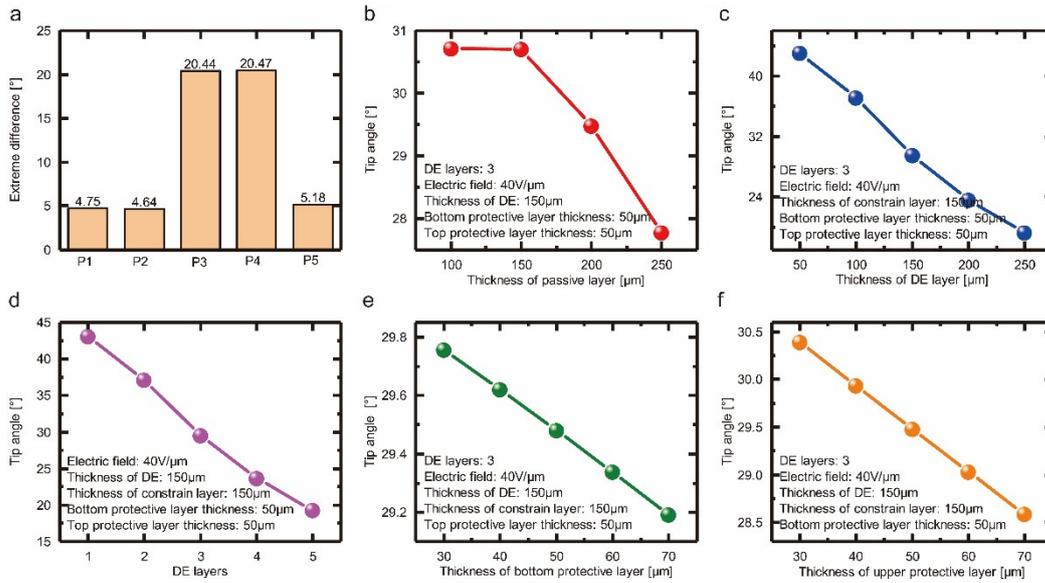
**Fig. S5.** Geometry of the multi-layer of FlexAM.



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162 **Fig. S6.** Diagram of incident angle and observation angle change for FlexAM under applied  
163 voltage.

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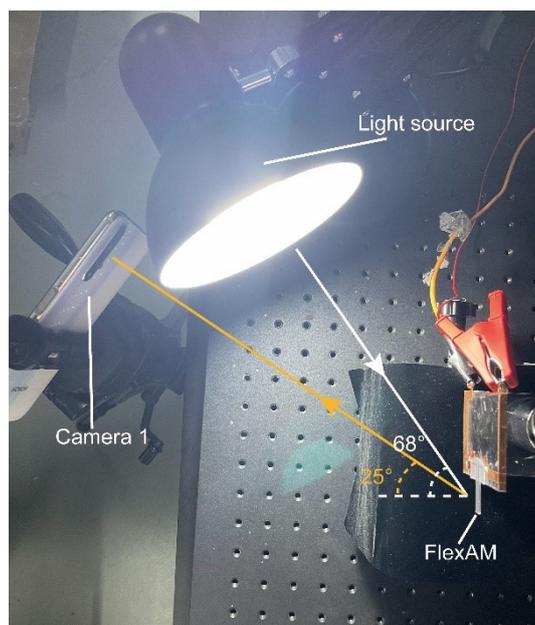
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167 **Fig. S7.** The influence of each parameter on the actuation effect. (a) The comparison of  
 168 extreme differences of each parameter derived from the orthogonal experiment calculation.  
 169 (b)-(d). The influence of multiple single parameters on the actuation performance.

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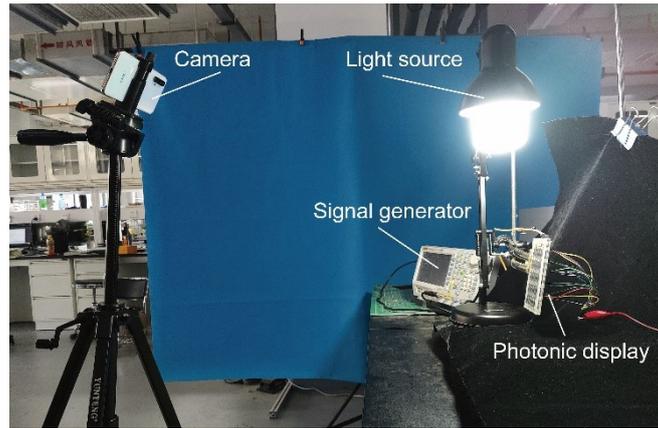
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173

174 **Fig. S8.** A camera of the mobile phone is used for recording FlexAM's color change under  
175 applied voltage.

176



177

178 **Fig. S9.** Arrangement of equipment for recording the patterning process of the photonic  
179 display.

180

181

**Table S1**

182

Parameters and specific values used for orthogonal experimental calculation

Parameters <sup>a)</sup>	Values				Range
Thickness of passive layer [ $\mu\text{m}$ ]	100	150	200	250	4.75
Thickness of bottom protective layer [ $\mu\text{m}$ ]	40	50	60	70	4.64
Thickness of DE layer [ $\mu\text{m}$ ]	100	150	200	250	20.44
DE layer number	2	3	4	5	20.47
Thickness of upper protective layer [ $\mu\text{m}$ ]	40	50	60	70	5.18

<sup>a)</sup>P1~P5 are used to represent the above five parameters for the convenience of subsequent presentation.

183

184

185 **Table S2**

## 186 The wavelength shift speed and wavelength range in different electrochromic methods

Actuation method	Author	Wavelength [nm]	Range [nm]	Response time [s]	Wavelength shift speed [nm·ms <sup>-1</sup> ]	Reference	Symbols
DE	This work	400-701	301	0.0565	2.814		⊗
DE	Baumberg et al.	673-733	60	0.1	0.6	Ref. <sup>1</sup>	■
		545-569	24				
DE	Qu et al.	629-737	108	0.5	0.302	Ref. <sup>2</sup>	▲
		581-732	151				
		600-657	57				
DE	Sun et al.	485-710	225	2.997	0.075	Ref. <sup>3</sup>	◆
DE	Chen et al.	470-650	180	0.095	0.84	Ref. <sup>4</sup>	★
DE	Ozin et al.	511-613	102	0.87	0.117	Ref. <sup>5</sup>	●
Solvent swelling	Shim et al.	568-633	65	20	0.00325	Ref. <sup>6</sup>	■
Solvent swelling	Puzzo et al.	433-691	258	10	0.0258	Ref. <sup>7</sup>	★
Solvent swelling	Yang et al.	470-620	150	150	0.001	Ref. <sup>8</sup>	●
Solvent swelling	Seo et al.	579.8-626.1	46.3	90	0.0005	Ref. <sup>9</sup>	▲
Solvent swelling	Wang et al.	510-719	209	25	0.00836	Ref. <sup>10</sup>	◆
Solvent swelling	Wu et al.	486-664	178	0.3	0.593	Ref. <sup>11</sup>	⬠
Electrophoresis	Yi	550-700	150	540	0.0003	Ref. <sup>12</sup>	■
Electrophoresis	Lee	480-630	150	0.5	0.3	Ref. <sup>13</sup>	●
Change refractive index	Du et al.	527-630	103	1.7	0.0606	Ref. <sup>14</sup>	■

Change refractive index	Huang et al.	618-661	43	1.5	0.0287	Ref. <sup>15</sup>	●
SMA <sup>a)</sup>	Zhao et al.	470-650	180	25	0.0072	Ref. <sup>16</sup>	■
TCPF <sup>b)</sup>	Zhao et al.	470-653	183	86.7	0.0021	Ref. <sup>17</sup>	■

<sup>a)</sup>SMA represents Shape Memory Alloy; <sup>b)</sup>TCPF represents Twisted and Coiled Polymer Fiber, which is an artificial muscle that shrinks by heat along its length.

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189 References

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